

Structural pattern extraction from asynchronous two-photon laser fault injection using spectral analysis

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Motivation (1/2)

- ❑ Pulsed laser testing is commonly used as an in-lab tool for Single-Event Effects sensitivity assesment & mapping
 - ❑ Among other applications: sensitivity pattern extraction for rate prediction

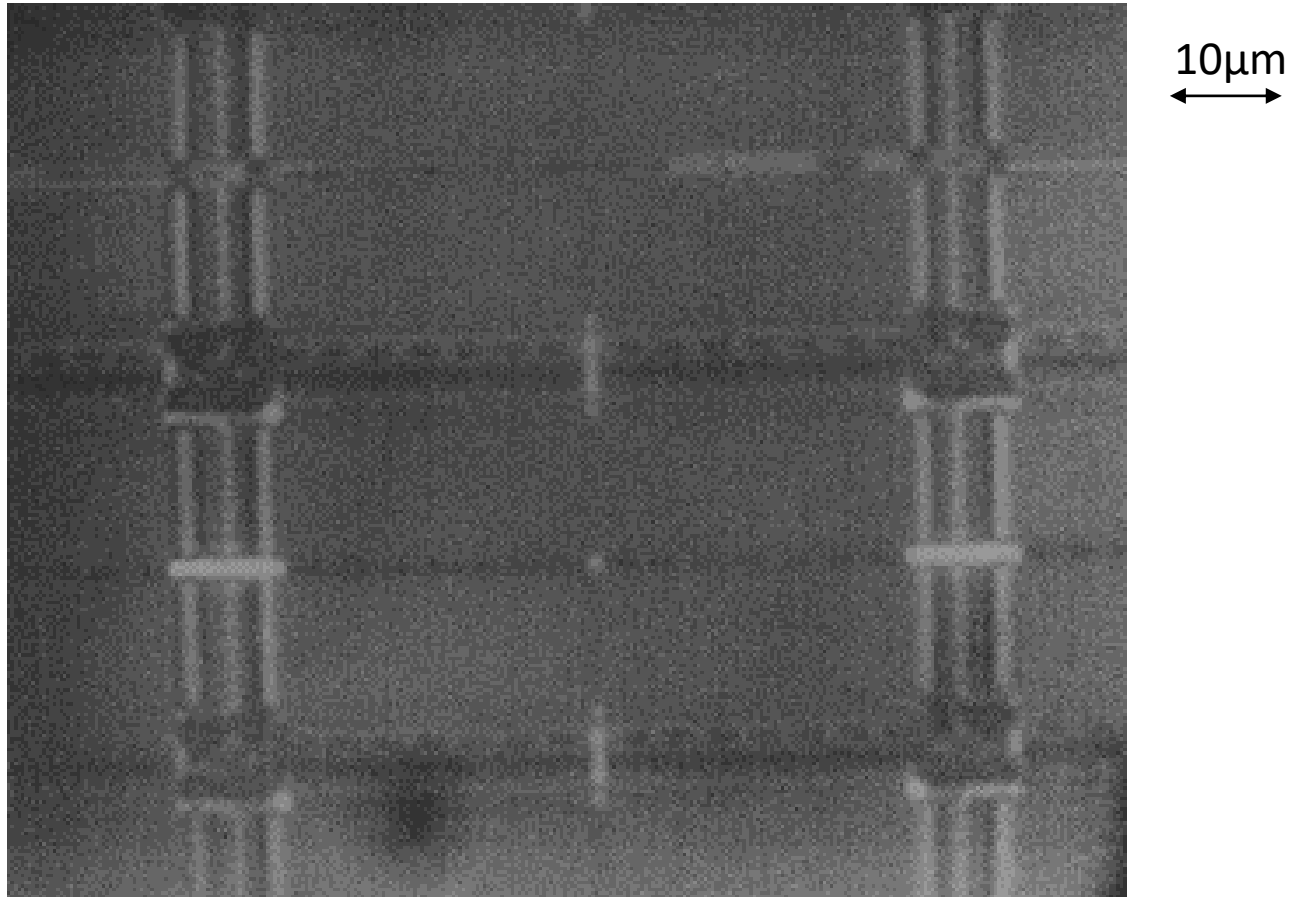
- ❑ Classical mapping approach:
 - ❑ Scanning + data acquisition
 - ❑ 1 (x,y) point \Leftrightarrow 1 pixel of the mapping \Leftrightarrow 1 measurement

- ❑ As most optical microscope-based techniques, laser testing of recent technologies is particularly demanding in terms of mechanical stability

- ❑ In a noisy environment, mapping repeatability can be challenging
 - ❑ Ex: Fan on the testboard, unstable air-cond., roadworks, wind in higher floors...

Motivation (2/2)

- Typical vibrations induced by fan on the testboard



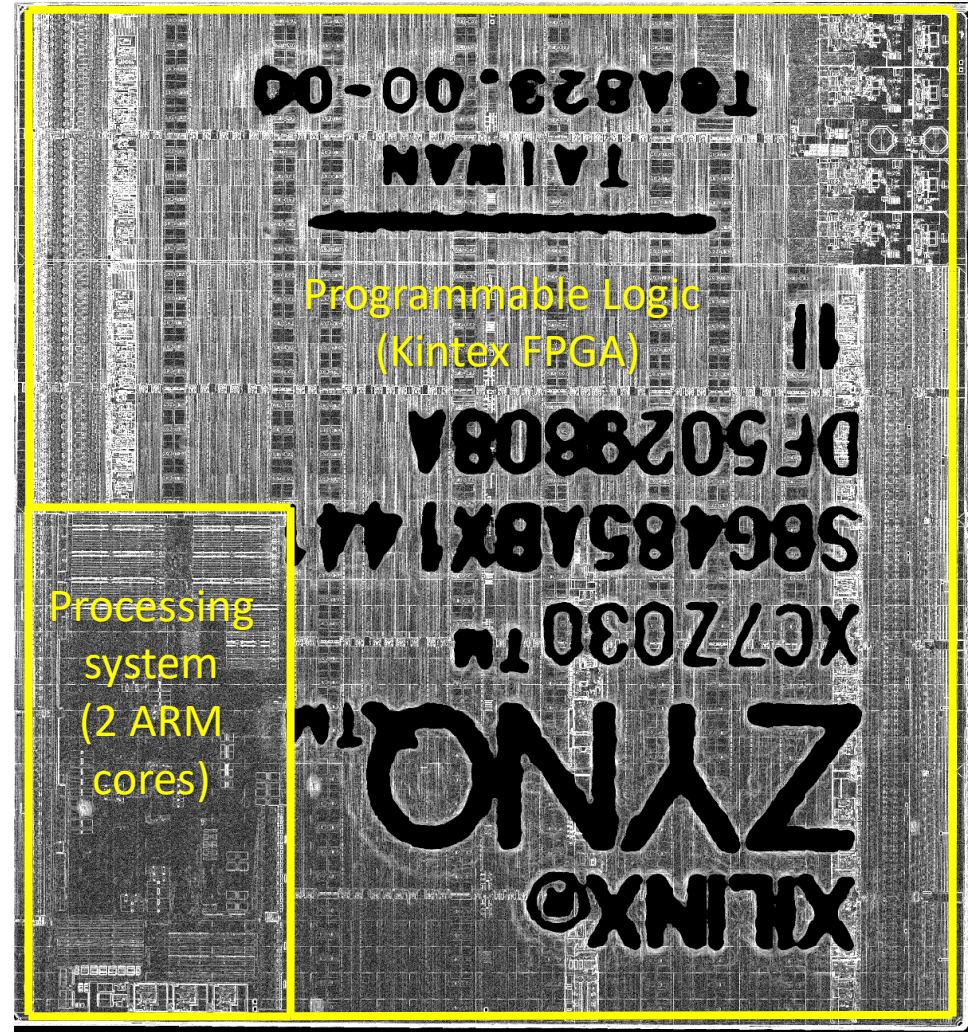
- This work: extracting structural information without mapping

Outline

- ❑ Device under test & set-up
- ❑ Testing method
- ❑ Experimental results
- ❑ Simulation
- ❑ Conclusions

Device under test

- ❑ XC7Z030 ZYNQ 7000 Programmable System on Chip (SoC)
 - ❑ TSMC HKMG 28nm CMOS process
 - ❑ Flip-chip lid-less package version provides easy access to the die backside
 - ❑ Substrate thickness: 700µm

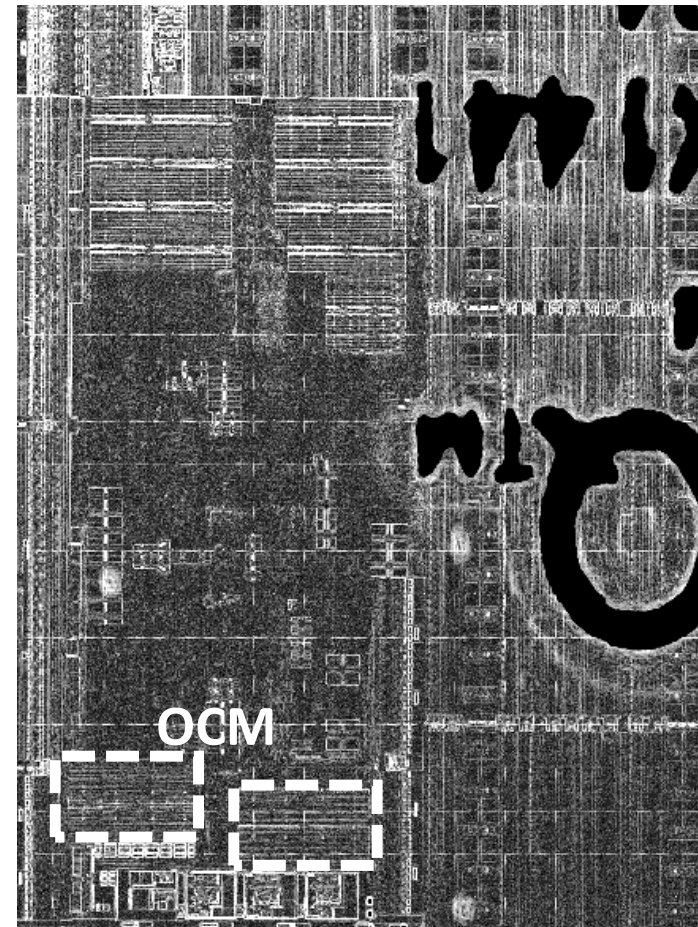


Region of interest

- ❑ On-chip memory (OCM)
 - ❑ 256KB SRAM
 - ❑ Shareable by both cores

- ❑ Critical section from a radiation-hardness assurance point of view when:
 - ❑ Used for cores synchronization
 - ❑ Used for software-level hardening

- ❑ Knowledge of the sensitive pattern required for event rate prediction



Laser testing set-up

- ❑ Two-photon absorption (TPA) microscope at IES
 - ❑ All-fiber laser source
 - ❑ Wavelength: $1.55\mu\text{m}$
 - ❑ Femtosecond pulses
 - ❑ Infrared imaging system



DUT testing method

❑ Self testing strategy

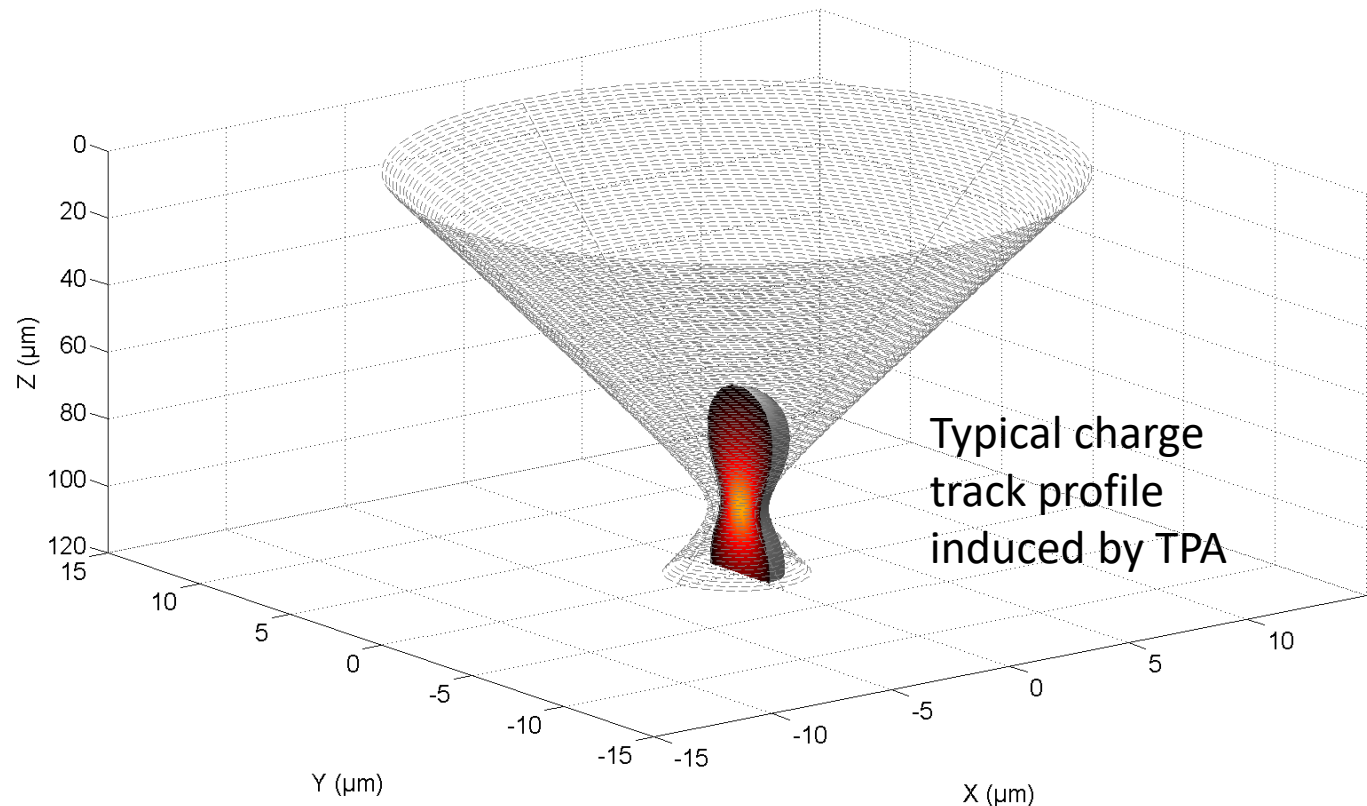
- ❑ Real-time test software operates on one of the CPU cores
- ❑ The program initiates, then periodically reads the OCM, report & correct errors
- ❑ The program instructions and data are stored in an external memory
 - ❑ Test program not impacted by errors in the OCM

❑ Asynchronous testing

- ❑ No synchronization between laser pulses, scanning motion and test loop
- ❑ Test loop period: $T_S = 150\text{ms}$
 - ❑ Not affected by errors detection and reporting
- ❑ Laser pulse period: $T_L = T_S + \varepsilon$
 - ❑ At most one laser pulse per test cycle => no false Multiple Cell Upset
 - ❑ Laser arrival time in the cycle different for each pulse = time-domain scan
 - ❑ Periodically, one test cycle without laser
 - ❑ Beating period: $T_B = T_L T_S / (T_L - T_S)$

Reminder: TPA-induced charge profile

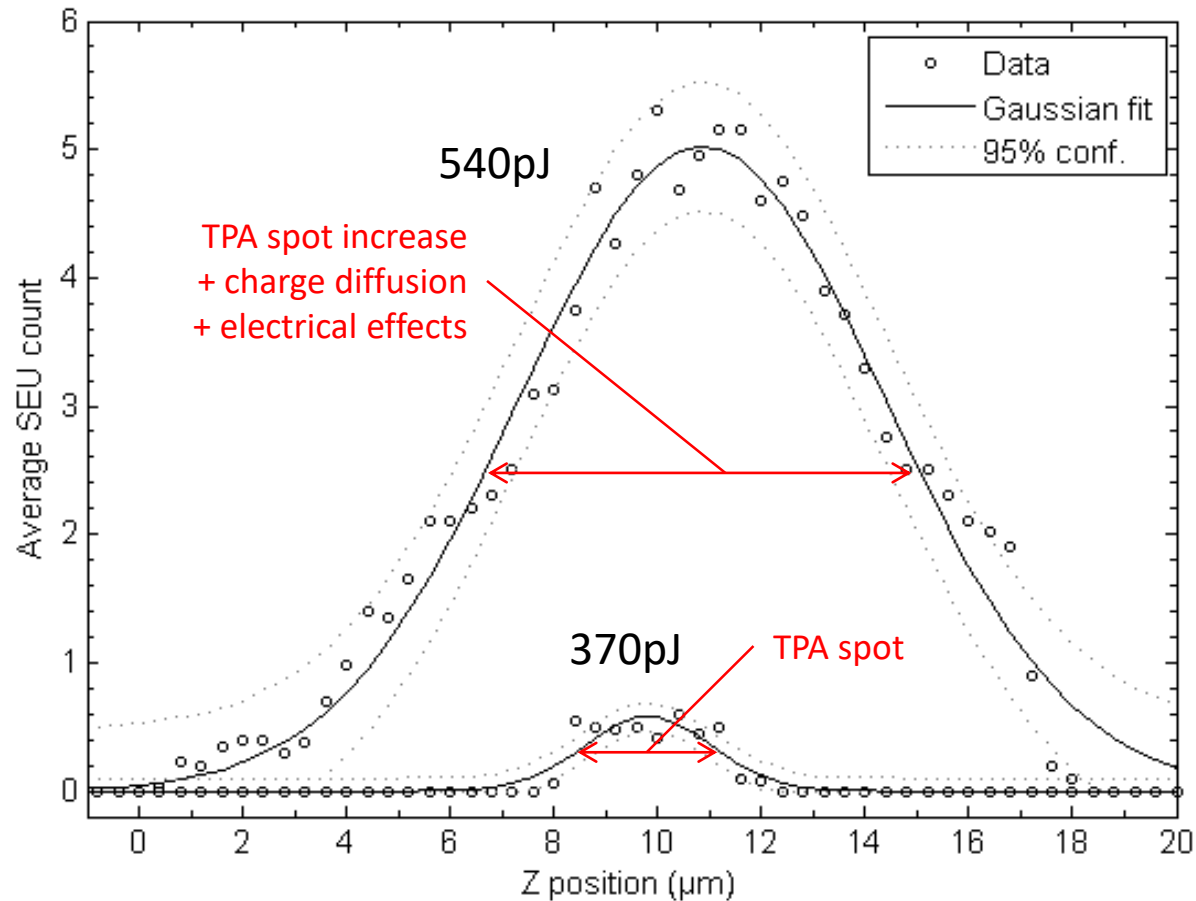
- ❑ Limited extension of the charge track along the optical axis
- ❑ Non-linear propagation effects in thick substrate
- ❑ Wavelength different from imaging wavelength
- ❑ => Offset between imaging focus and optimal laser focus



First steps: define optimal Energy and Focus

□ Depth scan

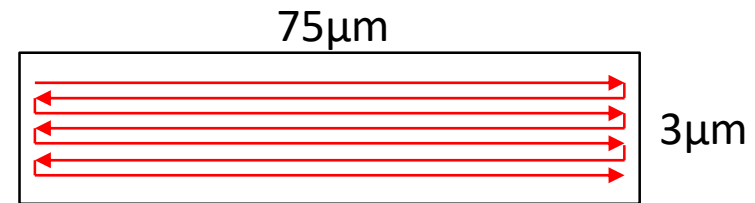
- Counting errors vs Z position, for different energies



- In the following: constant energy of 500pJ (tolerance to focus variations)

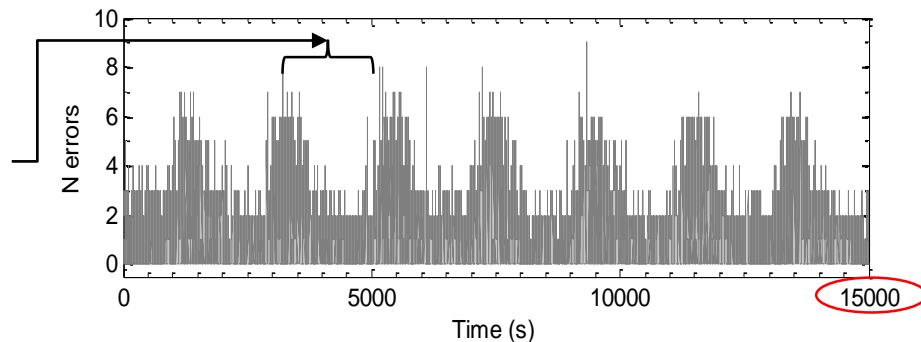
2D scan of an area in the OCM

- ❑ Area with high X/Y ratio
 - ❑ Continuous slow scan along X
 - ❑ 100nm steps along Y
- ❑ Scan repeated in a loop
 - ❑ Logging the number of errors detected in each test cycle



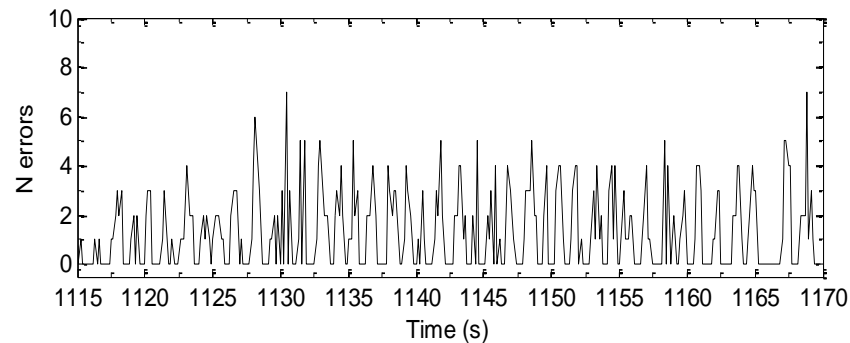
Long time scale:

Scan loop period
clearly identified



Short time scale:

Noisy « signal »



Error signal & noise sources

□ Error signal

- Described by the convolution of laser charge profile with DUT sensitivity pattern

Error signal Laser profile Sensitivity pattern

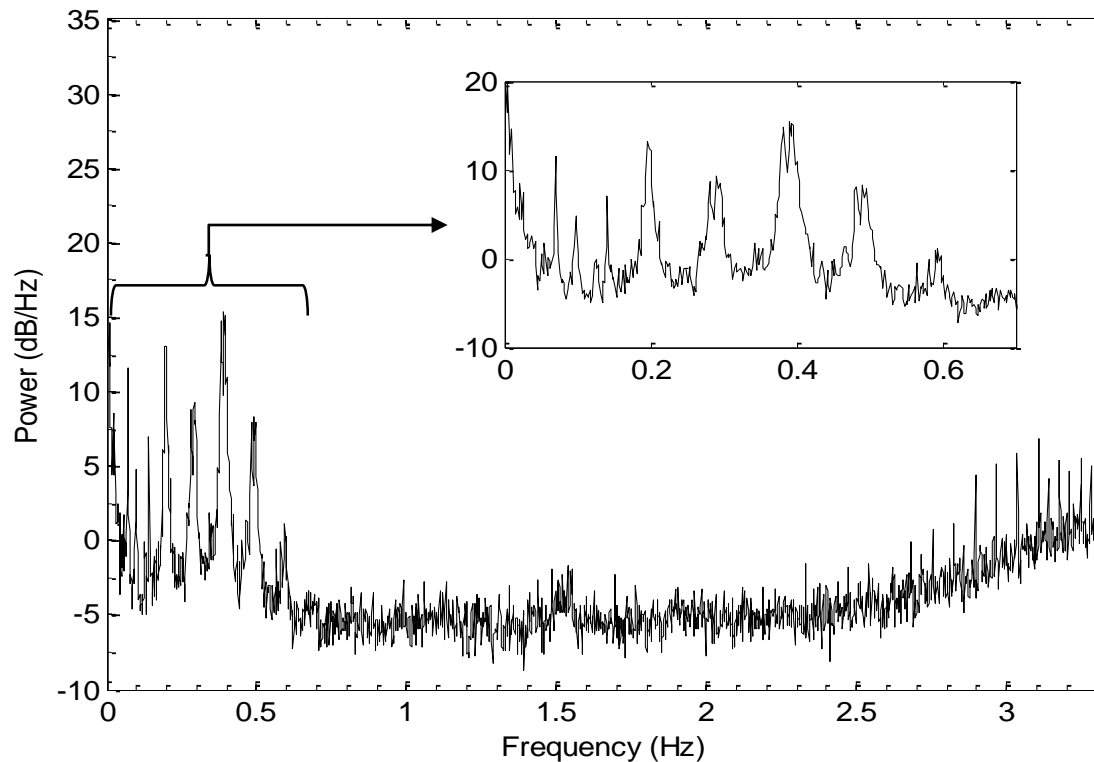
$$S(t) \propto \iiint L(\mathbf{r} - \mathbf{r}_L, \tau - t) P(\mathbf{r}, \tau) d\tau d\mathbf{r}$$

Modulation sources

- Energy fluctuations
- Thermal drift
- Vibrations
- Critical time window
- Chip activity
- Bias noise

⇒ Analysis in the frequency domain

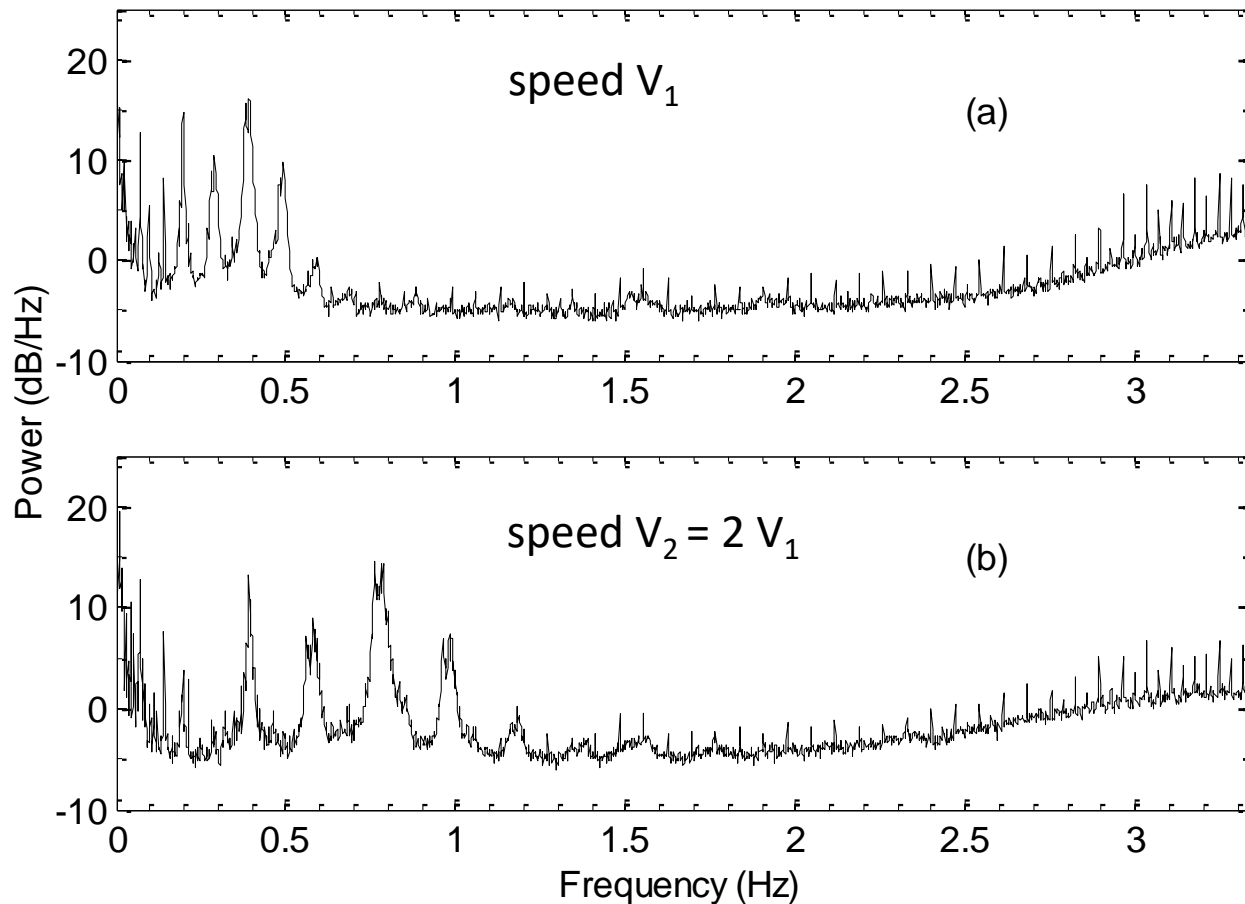
Error signal in the frequency domain



- ❑ Several strong peaks
 - ❑ Can some of them be related to a repetitive structure in the DUT ?

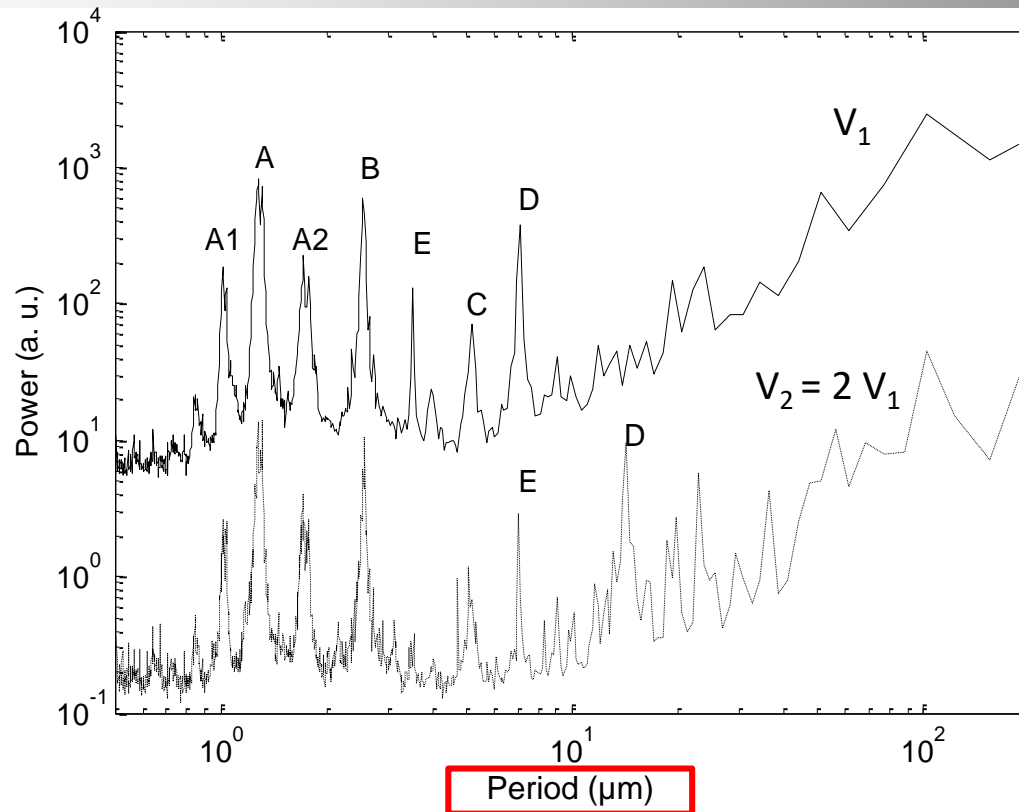
- ❑ How to distinguish between time-domain and space-domain modulations ?
 - ❑ ⇒ Repeat the same scan at a different speed

Scanning at 2 different speeds



- Peaks at same freq. = time-domain modulations
- Peaks at twice the freq. = space-domain modulations = DUT structural pattern
 - What are the corresponding dimensions ?

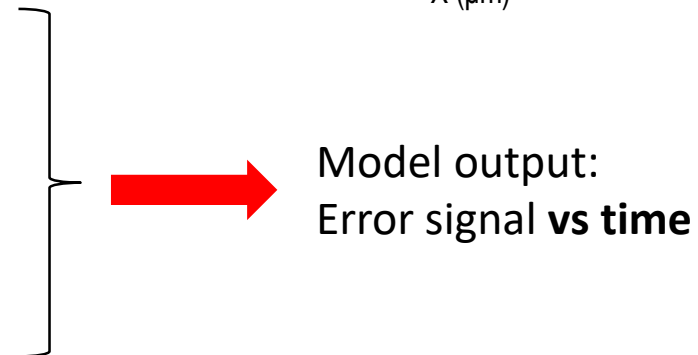
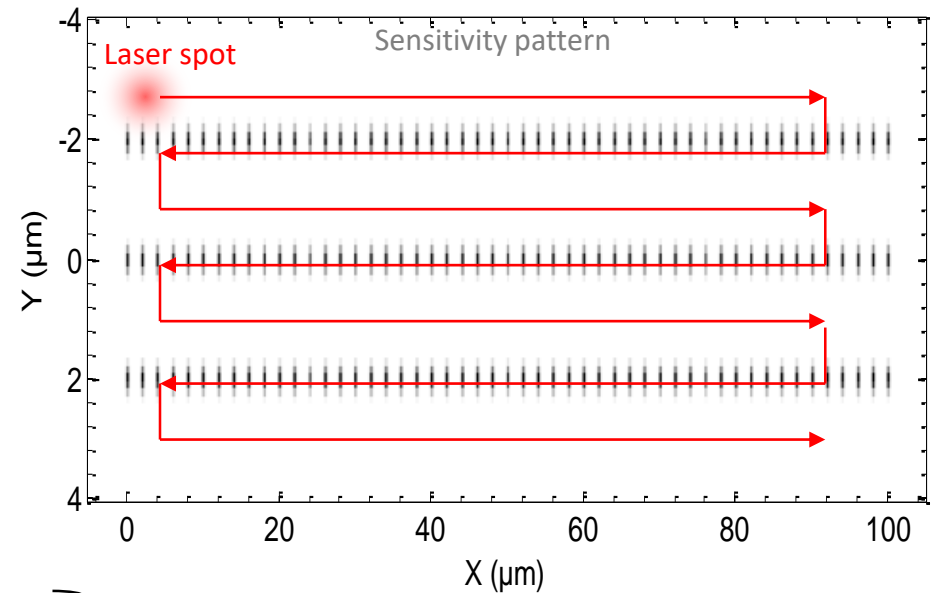
Plotting the results vs spatial period



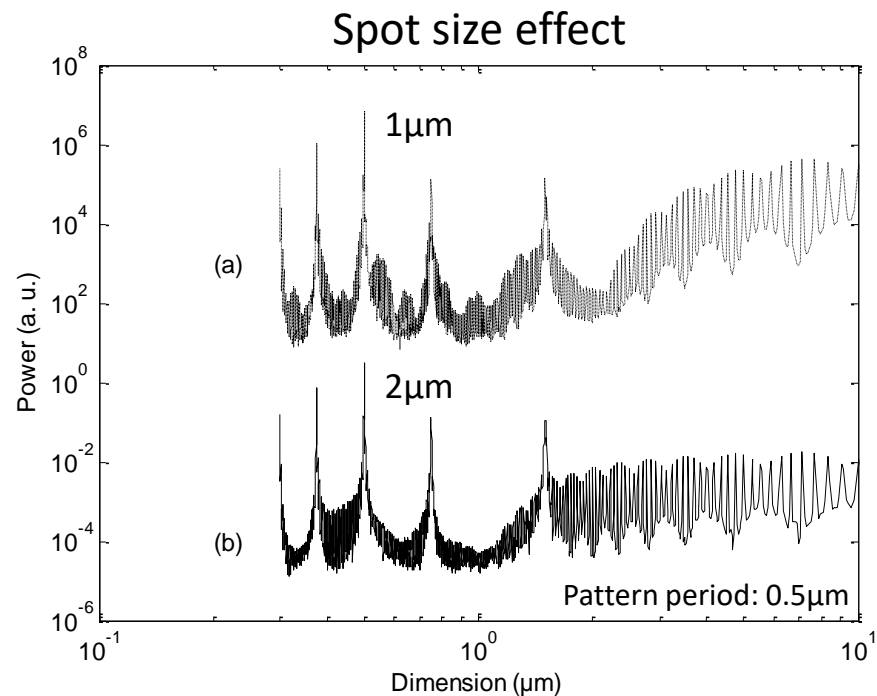
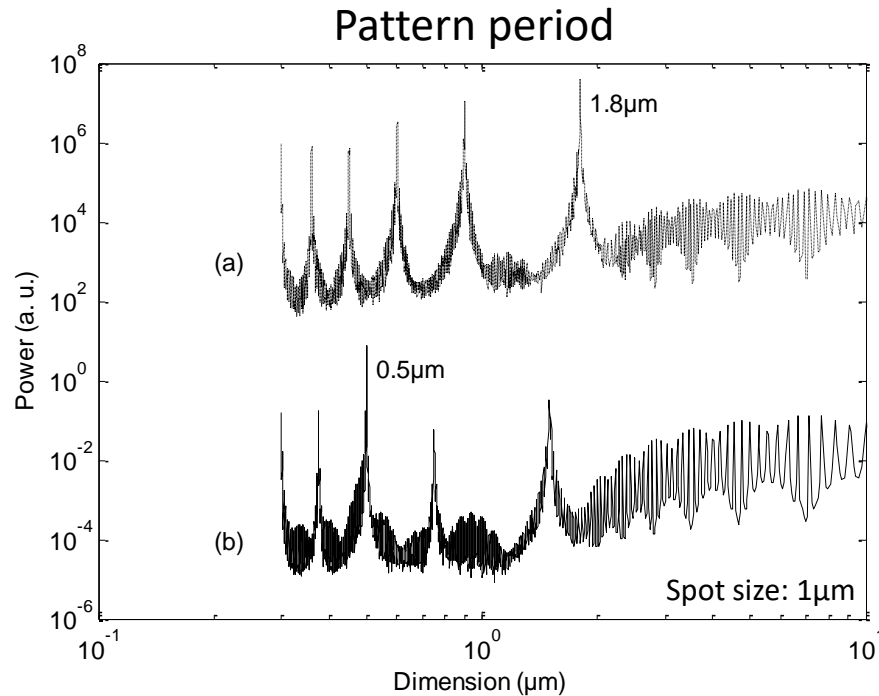
- Convert frequencies into spatial periods using $P = V / f$
- Peaks at same period = DUT structural pattern
- Peak A = $1.25\mu\text{m}$
 - Subwavelength pattern resolved from vibrations without any DUT synchronization

Modelling of the experiment

- ❑ Calculating the dynamic convolution of the laser charge track with a 2D sensitivity pattern
- ❑ Using a simple critical charge model for event generation
- ❑ Including every time-related aspect of the experiment
 - ❑ Scanning speed
 - ❑ Laser pulse frequency
 - ❑ Real-time test loop for event detection
- ❑ Including various noise sources
- ❑ Allows for quick estimation of the influence of experimental parameters



Modelling results



- ❑ Minimum detectable pattern: $d_{\min} = 2 \sqrt{T_s}$
- ❑ Pattern resolution not limited by spot size
 - ❑ No significant effect of the spot size on the spectrum

Conclusions

- ❑ Structural (sensitivity) pattern extraction from pulsed laser fault injection using slow scan and frequency-domain analysis of the error logs
- ❑ No synchronization required between laser, scanning and test equipment
- ❑ Sub-spot size and sub-wavelength periods extracted despite vibrations and multiple noise sources
- ❑ Accurate modelling of the scan timings shows limited effect of the spot size on the resolution
 - ❑ Resolution limited by speed, test loop period and detection mechanism (charge diffusion)
- ❑ Possible applications
 - ❑ Radiation effects: SEE sensitive pattern extraction
 - ❑ Security: reverse engineering for laser-based attacks
 - ❑ Failure analysis: pulsed laser stimulation techniques
- ❑ Future work
 - ❑ Working closer to the energy threshold to improve resolution
 - ❑ Automate spectrum processing to reconstruct more complex patterns (1D → 2D)